

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masaharu Nagai et al. Art Unit : Unknown
Serial No. : New Application Examiner : Unknown
Filed : October 29, 2003
Title : METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR
MANUFACTURING SEMICONDUCTOR DEVICE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Prior to examination, please amend the application as indicated on the following pages.

Amendments to the Specification begin at page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.